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List of Documents
Cited by Applicant

(Use several sheets if necessary)

Applicant: Michele VULPIO

Filing Date: October 24, 2003

Group: 1734

U.S. PATENT DOCUMENTS

Ex'r's In'l		Document Number	Date	Name	Class	Sub- class	Filing Date, if applicable
SM	AA1	5,356,477	October 18, 1994	Visser.			
SM	AA2	5,324,690	June 28, 1994	Gelatos et al.			

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Sub- class	Trans'l'n Yes/No
SM	AA3	0 299 249	January 18, 1989	Europe			Yes

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

SM	AA4	Raupp, G. B. et al. "Conformality of SiO ₂ sub 2/films from tetraethoxysilane-sourced remote microwave plasma-enhanced chemical vapor deposition", Journal of Vacuum Science and Technology (Vacuum, Surfaces and Films), May-June 1995 pp. 676-680, XP002143946.
SM	AA5	European Search Report for European Patent Application No. 00830153.3. dated July 31, 2001.

Examiner:

Date Considered: 2/28/04

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.